

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A method of forming a plurality of films on a base, the method comprising:

forming a first film of a plurality of films each of which includes a first material and a second material in a first area of the base, the forming of the first film including a first ejection of ~~a~~ the first material from a first nozzle and a ~~first~~ second ejection of ~~a~~ the second material from a second nozzle, the first ejection of the first material and the ~~first~~ second ejection of the second material being carried out during a first period; and

forming a second film of the plurality of films in a second area of the base and that is separated from the first film, the forming of the second film including a ~~second~~ third ejection of the first material from the first nozzle and a ~~second~~ fourth ejection of the second material from the second nozzle, the ~~second~~ third ejection of the first material and the ~~second~~ fourth ejection of the second material being carried out during a second period,

the first film being formed when the first ejection of the first material and the ~~first~~ second ejection of the second material during the first period are completed,

the base being provided in a first chamber during the first period,

~~the second film being formed when the second ejection of the first material and the second ejection of the second material during the second period are completed, and~~

the base being provided in the first chamber during the second period.

2. (Previously Presented) The method according to Claim 1,
the base being provided in an atmosphere that is adjusted to a pressure of 10^{-3} torr or less during at least a part of the first period.

3. (Previously Presented) The method according to Claim 1,

the base being provided in an atmosphere that is adjusted to a pressure of 10^{-5} torr or less during at least a part of the first period.

4. (Currently Amended) The method according to Claim 1, further comprising:
detecting a failure of the first ejection of the first material, the detecting
including a ~~third~~-fifth ejection of the first material from the first nozzle to a third area on the
base.

5. (Previously Presented) The method according to Claim 4,
the detecting detects the failure of the first ejection of the first material.

6. (Previously Presented) The method according to Claim 52,
the inspection of the preliminary film being performed by a measurement of
light-reflectivity of the preliminary film.

7. (Previously Presented) The method according to Claim 52,
the inspection of the preliminary film being performed by a measurement of
light-transmissivity of the preliminary film.

8. (Currently Amended) The method according to Claim 1, further comprising:
forming a third film of the plurality of films on the first film, the forming of
the third film including a ~~first~~-fifth ejection of a third material that is carried out during a third
period.

9. (Previously Presented) The method according to Claim 1,
the first material being ejected in a gaseous form from the first nozzle to the
first chamber during the first period.

10. (Previously Presented) The method according to Claim 9,
the first material being ejected in the gaseous form from the first nozzle to the
first chamber during the second period.

11. (Currently Amended) The method according to Claim 53,

the second material being ejected in a gaseous form from the third nozzle to the first chamber during a third period in which the ~~first-fifth~~ ejection of the third material from the third nozzle is carried out.

12. (Canceled)

13. (Currently Amended) The method according to Claim 8, further comprising:
forming a fourth film of the plurality of films on the second film, the forming of the fourth film including a ~~second-sixth~~ ejection of the third material that is carried out during a fourth period.

14. (Canceled)

15. (Previously Presented) A method of manufacturing an electronic device, the method comprising:
forming at least a part of an electronic device by using the method according to Claim 1.

16. (Previously Presented) The method according to Claim 15,
the first material being used for at least one of a conductive film, a semiconductor film, and an insulating film.

17. (Previously Presented) The method according to Claim 14, further comprising:
providing a pattern prior to the forming of the first film.

18. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:
forming at least a part of an electro-optical device by using the method according to Claim 1.

19. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:
the method according to claim 1,

the plurality of films being included in an electro-optical device.

20. (Previously Presented) The method according to Claim 19, further comprising:

forming partitions that surround each of the plurality of films.

21-30. (Canceled)

31. (Previously Presented) The method according to Claim 4,
the detecting the failure of the first ejection of the first material being carried out using a sensor.

32. (Previously Presented) The method according to Claim 1, further comprising:
sensing at least one film of the plurality of films.

33. (Previously Presented) The method according to Claim 32,
the sensing of the at least one film including an irradiation of the at least one film with a light source.

34. (Previously Presented) The method according to Claim 32,
the sensor measuring at least one of a transmission light that transmits the at least one film and a reflection light that is reflected by the at least one film.

35. (Currently Amended) The method according to Claim 1,
the first ejection of the first material from the first nozzle and the ~~first~~second ejection of the second material from the second nozzle during the first period is carried out at a first position of the first nozzle relative to the base, and

the ~~second~~third ejection of the first material from the first nozzle and the ~~second~~fourth ejection of the second material from the second nozzle during the second period is carried out at a second position of the first nozzle and the second nozzle relative to the base.

36. (Previously Presented) The method according to Claim 35,

further comprising:

moving a position of the first nozzle and the second nozzle relative to the base from the first position to the second position.

37. (Previously Presented) The method according to Claim 1,
the first nozzle and the second nozzle being among a plurality of nozzles provided in a discharge head.
38. (Previously Presented) The method according to Claim 1, further comprising:
sensing the first film by a sensor.
39. (Previously Presented) The method according to Claim 1, further comprising:
detecting a positional deviation between a first location on the base where the first film is actually formed and a second location on the base where the first film is to be formed.
40. (Previously Presented) The method according to Claim 18,
the electro-optical device including an organic electroluminescent element,
and
the first film being one of the plurality of films included in the organic electroluminescent element.
41. (Previously Presented) The method according to Claim 1,
the first nozzle and the second nozzle being among a plurality of nozzles,
a third material being ejected from a third nozzle of the plurality of nozzles during at least part of the first period, and
the first film including the first material, the second material and the third material.
42. (Previously Presented) The method according to Claim 1, further comprising:

performing a scanning movement of a head including the first nozzle and the second nozzle.

43. (Previously Presented) The method according to Claim 42,
the scanning movement of the head being performed during at least a part of a fifth period between the forming of the first film and the forming of the second film.

44. (Previously Presented) The method according to Claim 42,
the first nozzle and the second nozzle being among a plurality of nozzles provided in the head.

45. (Previously Presented) The method according to Claim 44,
a nozzle being constructed to adjust a posture of the nozzle by a θ direction adjusting mechanism, a Z direction adjusting mechanism, and a Y adjusting mechanism.

46. (Previously Presented) The method according to Claim 45,
each of the θ direction adjusting mechanism, the Z direction adjusting mechanism, and the Y adjusting mechanism being operated.

47. (Canceled)

48. (Previously Presented) The method according to Claim 1, further comprising:
setting a first relative position of the first nozzle and the second nozzle to the base before the forming of the first film is carried out; and

setting a second relative position of the first nozzle and the second nozzle relative to the base before the forming of the second film is carried out.

49. (Previously Presented) The method according to Claim 1, further comprising:
setting a first relative position of the first nozzle and the second nozzle relative to the base before the first ejection of the first material from the first nozzle and the second ejection of the second material from the second nozzle during the first period is carried out;
and

setting a second relative position of the first nozzle and the second nozzle relative to the base before the third ejection of the first material from the first nozzle and the fourth ejection of the second material from the second nozzle during the second period is carried out.

50. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:

forming at least a part of an electro-optical device by the method according to Claim 41,

each of the first film and the second film being at least a part of the electro-optical device.

51. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:

forming at least part of an electro-optical device by the method according to Claim 55,

each of the first film and the second film being at least a part of the electro-optical device.

52. (Previously Presented) The method according to Claim 5, a preliminary film being formed by the fifth ejection of the first material from the first nozzle to the third area provided on the base, and

the failure of the first ejection being detected based on an inspection of the preliminary film.

53. (Currently Amended) The method according to Claim 1, further comprising: forming a third film of the plurality of films that is formed in a third area provided on the base different from the first area and that is separated from the first film, the

forming of the third film including a ~~first~~fifth ejection of a third material from a third nozzle different from the first nozzle and the second nozzle.

54. (Currently Amended) The method according to Claim 1, further comprising:
forming a third film of the plurality of films that is formed in a third area of the base different from the first area, the forming of the third film including a ~~first~~fifth ejection of a third material from a third nozzle different from the first nozzle and the second nozzle that is carried out during the first period.

55. (Previously Presented) The method according to Claim 1,
a third material being ejected from the first nozzle during at least a part of the first period, and
the first film including the first material and the third material.

56. (Previously Presented) The method according to Claim 50,
an organic electroluminescent element being include in the electro-optical device, and
the first film being one of the plurality of films included in the organic electroluminescent element.

57. (Previously Presented) The method according to Claim 51,
an organic electroluminescent element being included in the electro-optical device, and
the first film being one of the plurality of films included in the organic electroluminescent element.

58. (Previously Presented) The method according to claim 4,
the detecting the failure of the first ejection of the first material is performed by spectroscopic means.